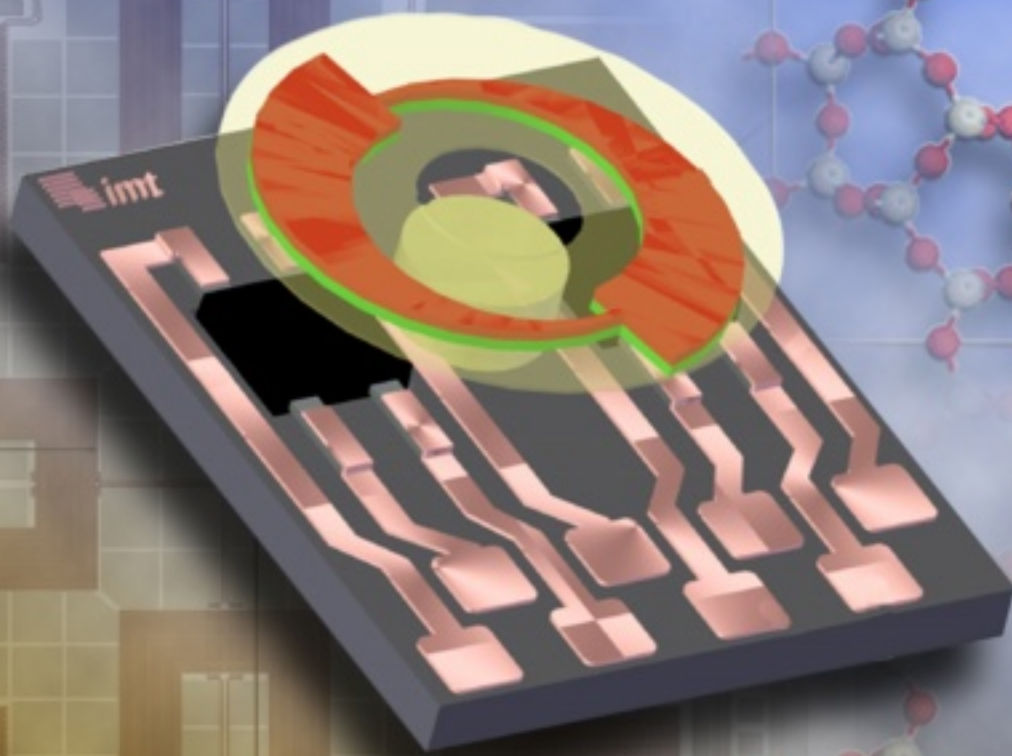


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Contents

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Research Articles

Foreword

Elena Gaura and James Brusey 1

A Novel Strain Gauge with Damping Capability

Xiaohua Li and Cesar Levy 5

A Parallel-Plate-Based Fishbone-Shape MEMS Tunable Capacitor with Linear Capacitance-Voltage Response

Mohammad Shavezipur, Patricia Nieva, Seyed Mohammad Hashemi and Amir Khajepour 15

Micro-Fabricated Rotational Actuators for Electrical Voltage Measurements Employing the Principle of Electrostatic Force

Jan Dittmer, Rolf Judaschke and Stephanus Büttgenbach 25

Nanochip: a MEMS-Based Ultra-High Data Density Memory Device

Nickolai Belov, Donald Adams, Peter Ascanio, Tsung-Kuan Chou, John Heck, Byong Kim, Gordon Knight, Qing Ma, Valluri Rao, Jong-Seung Park, Robert Stark, Ghassan Tchelepi 34

Vertically Aligned Carbon Nanotube Array (VANTA) Biosensor for MEMS Lab-on-A-Chip

Luke Joseph, Thomas Hasling and David Garmire 47

Development and Test of a Contactless Position and Angular Sensor Device for the Application in Synchronous Micro Motors

Andreas Waldschik, Marco Feldmann and Stephanus Büttgenbach 56

A Robust Miniature Silicon Microphone Diaphragm

Weili Cui, Ronald N. Miles and Quang Su 63

Analysis of an Electrostatic MEMS Squeeze-Film Drop Ejector

Edward P. Furlani 78

Application of Nonlocal Elasticity Shell Model for Axial Buckling of Single-Walled Carbon Nanotubes

Farzad Khademolhosseini, Nimal Rajapakse, Alireza Nojeh 88

An Online Tool for Simulating Electro-Thermo-Mechanical Flexures Using Distributed and Lumped Analyses

Fengyuan Li and Jason Vaughn Clark 101

Monte Carlo Simulation Studies for the Templated Synthesis of Ni Nanowires in Zeolites

Javier A. Huertas-Miranda, María M. Martínez-Iñesta 116

A Multiscale Model of Cantilever Arrays and its Updating

Michel Lenczner, Emmanuel Pillet, Scott Cogan and Hui Hui 125

Simulation of Droplet Dynamics and Mixing in Microfluidic Devices using a VOF-Based Method <i>Anurag Chandorkar, Shayan Palit</i>	136
Comparison of Transmission Line Methods for Surface Acoustic Wave Modeling <i>William Wilson, Gary Atkinson</i>	150
Micro Tools with Pneumatic Actuators for Desktop Factories <i>Björn Hoxhold and Stephanus Büttgenbach</i>	160
Hearing Aid Sensitivity Optimization on Dual MEMS Microphones Using Nano-Electrodeposits <i>Sang-Soo Je, Jeonghwan KIM, Michael N. Kozicki, and Junseok Chae</i>	170
A Novel Virtual Button User Interface for Determining the Characteristics of an Impulse Input Based on MEMS Inertial Sensors <i>A. J. Zwart, G. M. Derige, D. Effa, P. Nieva, S. Lancaster-Larocque</i>	179
Magnetic Bead and Fluorescent Silica Nanoparticles Based Optical Immunodetection of Staphylococcal enterotoxin B (SEB) in Bottled Water <i>Shiva K. Rastogi, Veronica J. Hendricks, Josh R. Branen and A. Larry Branen</i>	191
Wireless Sensor Networks for Space Applications: Network Architecture and Protocol Enhancements <i>Driss Benhaddou, Manikanden Balakrishnan, Xiaojing Yuan, Ji Chen, Mukesh Rungta, Rick Barton, Heng Yang</i>	203
Classifying Transition behaviour in Postural Activity Monitoring <i>James Brusey, Ramona Rednic and Elena Gaura</i>	213

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Development and Test of a Contactless Position and Angular Sensor Device for the Application in Synchronous Micro Motors

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Abstract: In this work, we present a contactless micro position and angular sensor system which consists of fixed commercial magnetic sensor elements, such as hall sensors and a movable part with integrated micro structured polymer magnets. This system serves particularly for linear and rotatory synchronous micro motors which we have developed and successfully tested. In order to achieve high precision and control of these motors an integration of the special micro position and angular sensors is pursued to increase the resolution and accuracy of the devices. *Copyright © 2009 IFSA.*

Keywords: Synchronous micro motors, Micro coils, UV depth lithography, Polymer magnets, Position sensor

1. Introduction

Due to the development of several electromagnetic micro actuators and motors, like linear and rotatory reluctance micro steppers as well as a special “Lorentz force actuators”, the demand of suitable position detection systems has increased. In the last years, we have developed and fabricated linear and rotatory synchronous motors with axially magnetized polymer magnets or commercial magnets in disc shape rotor design (Fig. 1) [1-3]. Their basic design consists of electrical conductors and coil systems as well as of magnetic materials that were fabricated in additive technology via UV-depth lithography and electroplating. Furthermore, special micro composites were developed. This allowed the fabrication of micro magnets with arbitrary shape and properties, ensuring complete compatibility to existing process chains [4]. Thereby the integration of the position detection system into these synchronous motors by already used technologies is possible.

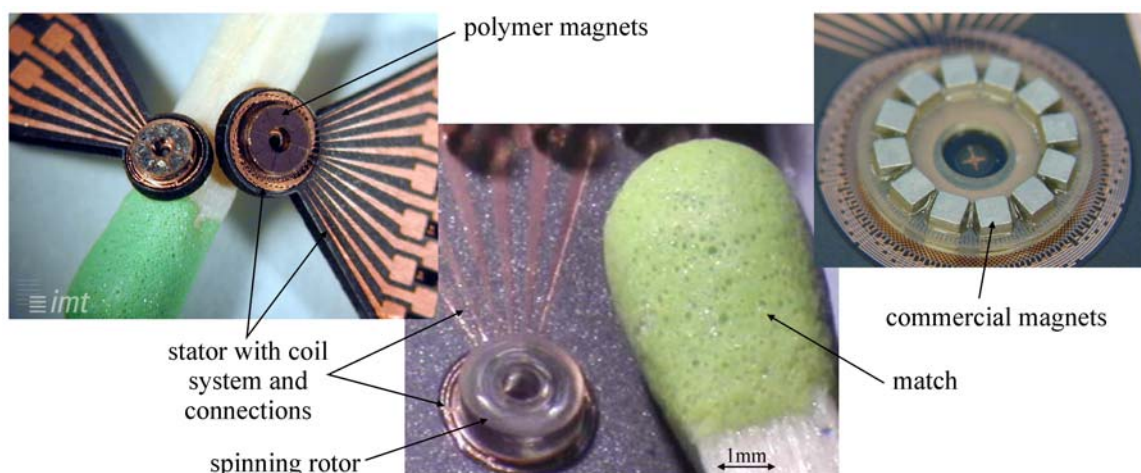


Fig. 1. Synchronous micro motors with integrated polymer magnets and commercial magnets.

2. Concept and Design

The sensor device consists of a Hall sensor element and a magnetic structure implemented in a rotor disc which is adjusted above the sensor (Fig. 2, left). The Hall sensor detects the strength of axial magnetic field generated by the magnetic structure. Due to the varying geometry of the magnetic structure, the strength of the magnetic field can be altered by moving it over the magnetic sensor. This results in the detection of the geometric structures as well as the measurement of their corresponding angle. The Hall sensor is purchased from ‘Chen Yang Technologies’. This component has an overall size of $3.5 \times 1.5 \times 0.6 \text{ mm}^3$ and features a high linearity in the range between 0 and 300 mT.

For the first test different geometries are applied as magnetic structure in the rotor: single and double cotters, step like cotters and segmented structures (Fig. 2, right).

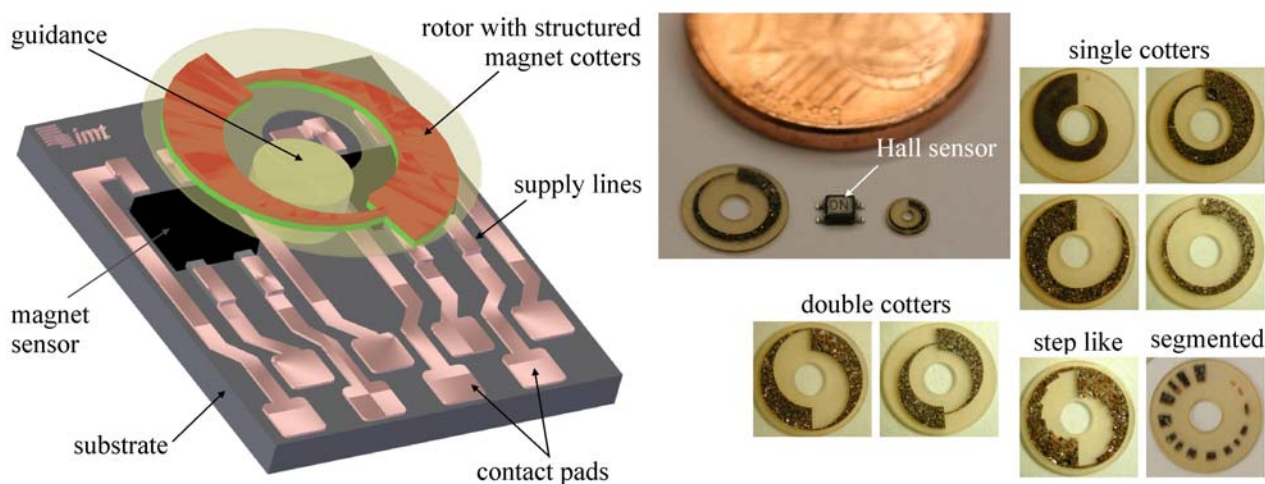


Fig. 2. Concept of the sensor device (left) and rotors with implemented magnetic structures (right).

3. Characterization of Polymer Magnets

Polymer magnets are micro composite materials which are fabricated by embedding powdery, magnetically hard materials in a polymer matrix. Three different fabrication techniques were

developed for micro scale structuring of these composites: direct structuring, lift-off process and soft lithographic molding [5]. Different qualities and properties can be obtained depending on the used technique. In comparison to electroplated or sputtered layers the lift-off process provides magnetically hard structures with high thicknesses of some 100 μm combined with high edge quality and high aspect ratios. The advantage of this integration technique is the possibility to fabricate structures with arbitrary shapes and thicknesses.

Various magnet powders were used and characterized for applications as polymer magnets, like rare earth materials (neodymium-iron-boron, samarium-cobalt) and ferrites (barium-, strontium-ferrites). The fabricated polymer magnet structures were characterized regarding their magnetic properties with a vibrating sample magnetometer (LakeShore Inc.). In Fig. 3 (left) the magnetization curves are shown for various used polymer magnets with 80 % wt powder ratio and structure heights of 320 μm .

For the implementation different geometries of polymer magnet structures were previously fabricated to determine the magnetic properties in dependence of the dimensions. The magnetization characteristics of different square polymer magnet structures made of neodymium-iron-boron are shown in Fig. 3 (right). Maximal remanences between 230 mT and 345 mT were obtained with neodymium-iron-boron powder.

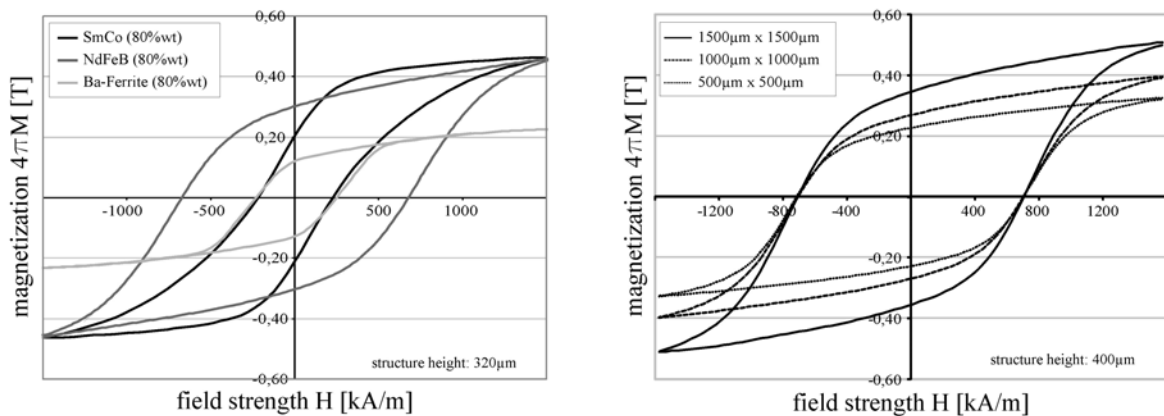


Fig. 3. Magnetization characteristics of polymer magnets made of different materials (left) and different dimensions made of neodymium-iron-boron (right).

3. Fabrication

For fabrication of the sensor system the hall sensor is assembled on the substrate and integrated into the micro fabrication process chain; thereby allowing high precision adjustment and electrical contacting through the combination of UV-depth lithography and copper electroplating. The rotor is made in a separate process.

The process sequence for the fabrication of the rotor element is shown in Fig. 4. It starts with electroplating of a sacrificial copper layer. On this a thin SU-8 layer is patterned serving as a base plate. A following SU-8 layer with thickness of about 300 μm is structured to create a high precision form with an arbitrary geometry, which is only limited by the lithography step. The unused areas around the mould and the guidance structure are filled with a soluble resist like AZ9260. After that, the liquid magnetic composite is inserted in the mould and baked out. Subsequently, a polishing process follows to level the compound structure and to remove waste residues. Finally, the sacrificial copper layer is etched and the rotors are detached from substrate. In doing so several magnetic structures were fabricated.

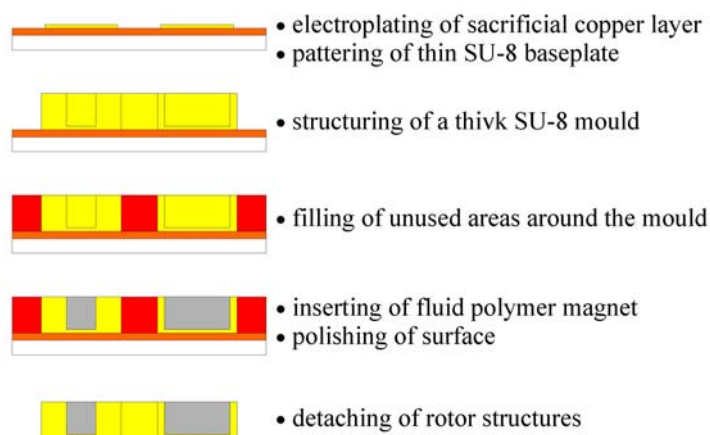


Fig. 4. Process sequence for the rotor fabrication.

For the magnetization of the polymer magnet cutter structures, special magnetization equipment was designed. It consists of a ferromagnetic core with a yoke, in which a magnetization adapter with a ring structure can be placed (Fig. 5). A flat coil with 445 windings wound around the core serves for generating the magnetic flux. With the equipment a magnetic flux density of nearly 2.1 T is reached in the air gap or polymer magnet respectively what is adequate for a permanent axial magnetization.

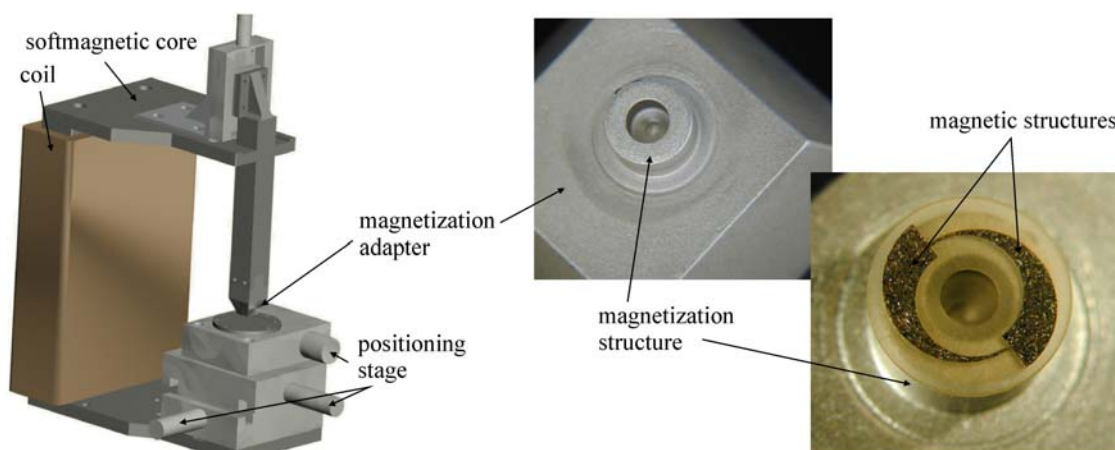


Fig. 5. Magnetization equipment (left) and adapter (right).

4. Measurements

4.1. Static Measurements

For the first tests an automatic measuring system was developed. This system allows the positioning of the magnet sensor to the polymer magnet and controls all measurement parameters (Fig. 6, left). Therewith a detailed parameter study can be run to optimize the sensor device.

To improve the sensor device performance, different magnetic structures were tested, which differ in the number and the shape of cutters. One static measurement of a complete rotation of a double cutter over one hall sensor is shown in Fig. 6 (right). The characteristic of Hall voltage mirrors the form of signal structure. The rising between low and high level proceeds approximately linear with a different voltage of 12 mV measured by an input current of 5 A.

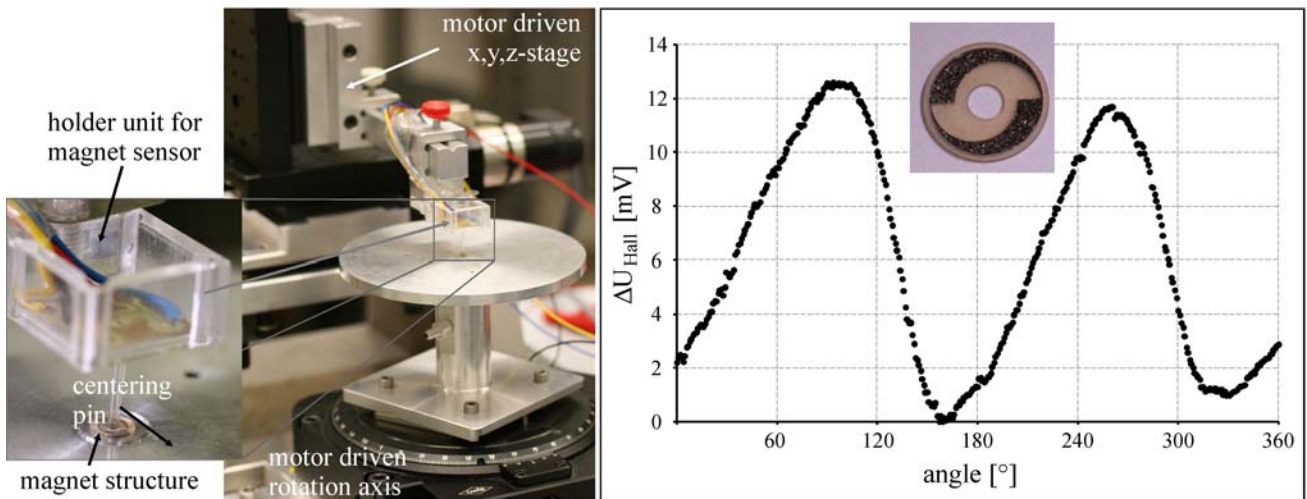


Fig. 6. Measurement setup with motorized stage and automated control for static measurements (left); and characteristic of a double cotter for a rotation of 360° (right).

4.2. Dynamic Measurements

There is a requirement of high dynamic response behavior for the application in the synchronous motors. Hence, dynamic measurements were carried out with a modified set up (Fig 7, left). A commercial DC-motor is used for varying the rotational speed. An additional electromagnetic shielding is fixed on the top of the motor to avoid influences on the measurements due to the magnetic field of the motor.

The rotor is adjusted on an adapter which is form-closed mounted on the motor shaft. The Hall sensor is aligned by a three axis positioning stage. Because of this measurement set up the sensor could be placed with a height distance of 10 μm to the rotor. The characteristics of Hall voltage were recorded for different rotational speeds. The results for a double cotter are shown in Fig. 8 (right). In the area between low and high level, the voltage proceeds almost linearly independent of the rotational speed.

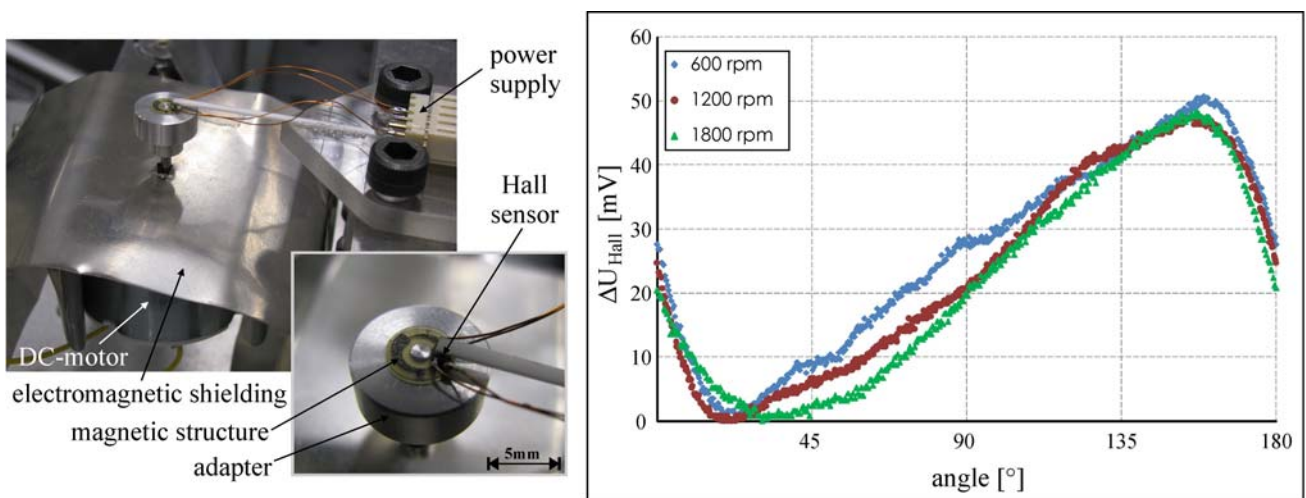


Fig. 7. Set up for dynamic measurements (left); and measurement results of a double cotter for different rotational speeds (right).

A comparison between single and double cotter rotor is shown in Fig. 8 (left). The high and low voltage levels are equal. However, the double cotter features a steeper rising when compared to the single one. Furthermore, the single cotter characteristic shows some fluctuations. This is caused by a small-scale unbalance in z-direction. A major influence is given by the grain size of the constituted magnet powder. Such fluctuations could appear due to inhomogeneous grain size ($>9 \mu\text{m}$) or unequal distribution of the NdFeB powder. The likewise tested ferrite powder possesses a finer grain size ($<1.5 \mu\text{m}$). In Fig. 8 (right) a comparison between ferrite and NdFeB magnet double cotter structures is depicted. The signal structure made of NdFeB indicates a three- to fourfold higher magnetization and therewith higher Hall voltage. This corresponds with a sensitivity of 0.3 mV per degree for the NdFeB structure and 0.09 mV per degree for the ferrite structure. A summary of the measured values and resultant sensitivities are listed in Table 1.

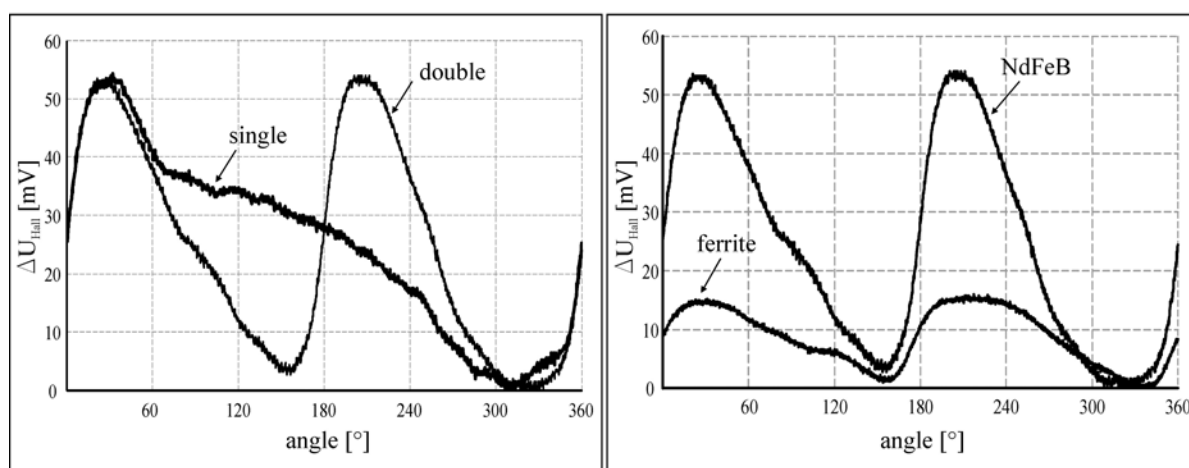
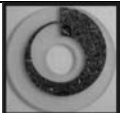




Fig. 8. Comparison of single and double cotter made of NdFeB-polymer magnet (left); and comparison of double cotters with different polymer magnet materials.

Table 1. Overview of measured signal differences and calculated sensitivities.

Signal Structure	Material	Signal Difference [mV]	Sensitivity [mV/°]
	ferrite	16-20	0.04-0.06
	NdFeB	49-60	0.14-0.17
	ferrite	14-17	0.08-0.09
	NdFeB	48-54	0.27-0.30
	ferrite	16	0.09
	NdFeB	56	0.31

5. Conclusion and Outlook

The purpose of this work was to develop a position detection system for electromagnetic actuators. The concept of such a system based on the Hall Effect was presented and the fabrication of rotatory signal structures was identified. Furthermore, first measurements for the characterization of this system were carried out and evaluated. The results show that with NdFeB powder based structures nearly

linear characteristics with good sensitivities can be achieved. In respect of the signal structures no substantial difference could be determined between step like variants and the other ones.

Two important aspects will be aimed for the further optimization and application. Thus, unpacked Hall sensor elements should be applied, which are integrated in the process chain for fabrication of the synchronous motors. Furthermore, the synchronous motor will be provided with two Hall sensor elements. A first example has already been realized (Fig. 9). Due to a convenient combination of measured Hall voltages of both sensor elements the sensitivity could be increased and therewith more precise position detection could be provided.

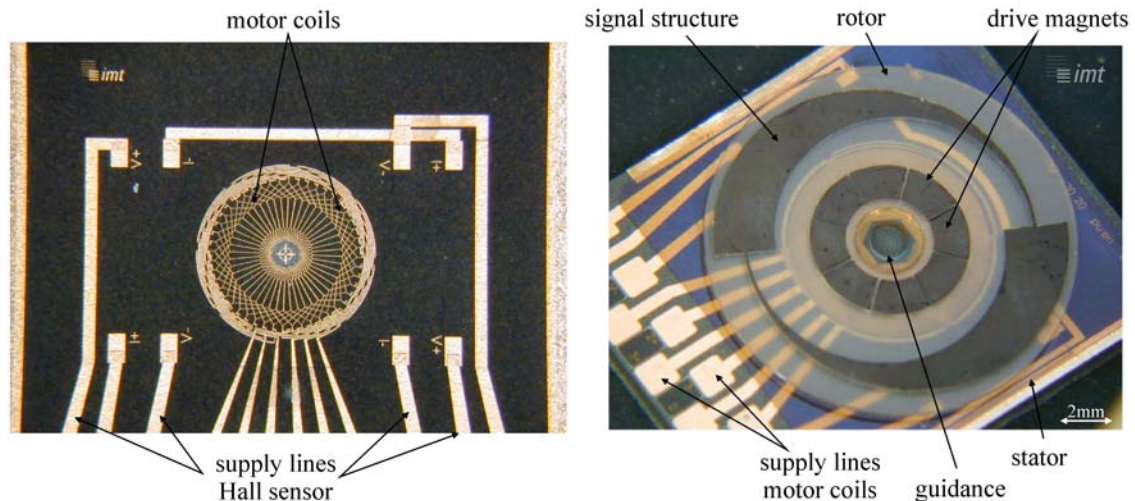


Fig. 9. Synchronous motor with integrated sensor structure for position detection.

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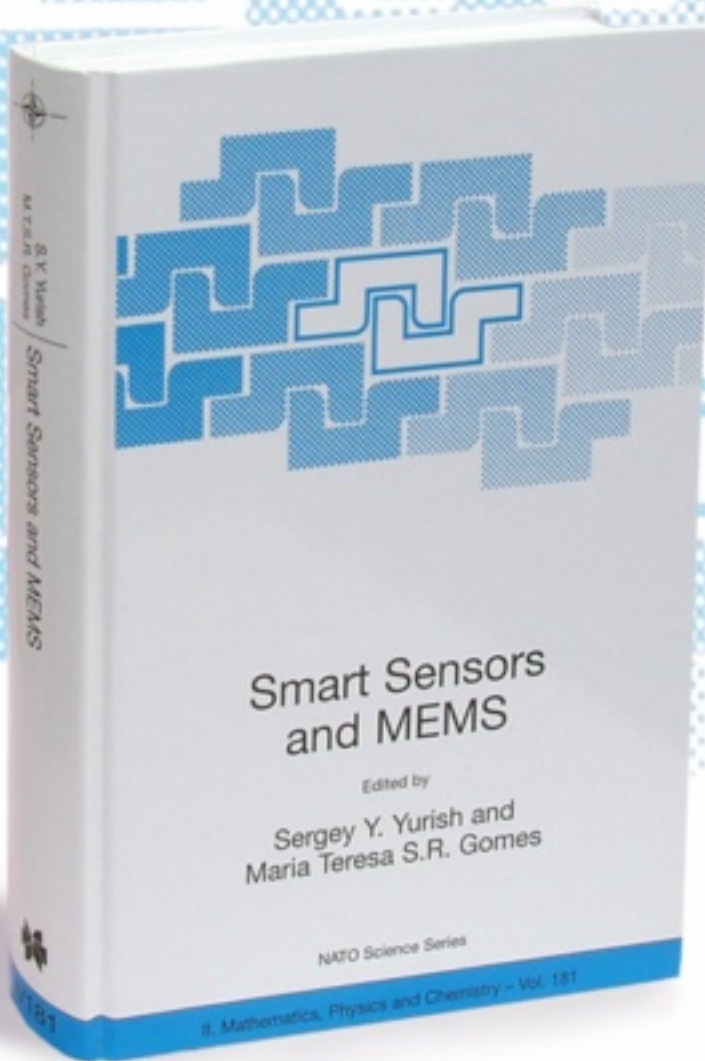
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